

IN THE CLAIMS

10/552539

Please amend the claims as follows:

1. (currently amended) A method for producing a preform for optical fibers [~~by~~] , said method comprising: producing a fluorine-doped SiO₂ cladding glass [(4)] on a core glass cylinder [(3)] rotating about [its] a longitudinal axis thereof, including feeding [~~in that~~] a plasma burner [(1)~~is fed~~] with a silicon-containing starter substance, said starter substance being [~~is~~] oxidized in a plasma flame [(2)~~assigned to~~] of the plasma burner [(1)] to obtain SiO₂ particles, and depositing the SiO₂ particles [~~are deposited~~] in layers on a [~~the~~] cylindrical outer surface of the core glass cylinder [(2)] in the presence of fluorine and sintering said SiO₂ particles deposited [~~are sintered~~] into the cladding glass [(4)], wherein [characterized in that a] said plasma flame [(2)~~which~~] emits ultraviolet light [~~of~~] in one or more wavelengths in a range about a wavelength of 214 nm [~~with~~] at an intensity of at least 0.9 μW, determined on the basis of [~~the~~] a plasma flame intensity measurement, [~~is used for~~] during the forming and depositing of the SiO₂ particles on the core glass cylinder [(3)].
2. (currently amended) The method according to claim 1, [characterized in that a] wherein the plasma flame [(2)~~is used which~~] emits said ultraviolet light [of a wavelength of 214 nm with] at an intensity ranging from 1.0 μW to 1.4 μW.
3. (currently amended) The method according to [any one of the preceding claims, characterized in that] claim 1, wherein the cylindrical outer surface of the core glass cylinder [(3)] is kept at a surface temperature ranging from 1550°C to 2000°C during

deposition of the SiO₂ particles, and [~~that~~] wherein the core glass cylinder [(3)] has an outer diameter of at least 40 mm.

4. (currently amended) The method according to claim 3, [~~characterized in that~~] wherein the cylindrical outer surface of the core glass cylinder [(3)] is kept at a surface temperature ranging from 1700°C to 1900°C during deposition of the SiO₂ particles, and [~~that~~] wherein the core glass cylinder [(3)] has an outer diameter of at least 60 mm.

5. (currently amended) The method according to claim 1, wherein [any one of the preceding claims, characterized in that] the SiO₂ particles are deposited on the cylindrical outer surface in layers having [with] a layer thickness [~~in~~] such [~~a manner~~] that optical fibers derived from the preform have optical fiber [they yield] layers yielded by the layers of the deposited SiO₂ particles, and said optical fiber layers have respective [with] layer thicknesses of not more than 0.05 µm in the optical fibers.

6. (currently amended) A method for producing a preform for optical fibers [~~by~~] , said method comprising:

providing a cladding glass tube [~~consisting~~] of fluorine-doped quartz glass for cladding a core glass cylinder, wherein said cladding glass tube is produced by supplying [with] a silicon-containing starter substance [~~being supplied~~] to a plasma burner [~~for producing the cladding glass tube~~], said plasma burner having a plasma flame that oxidizes said substance [~~being oxidized in a plasma flame assigned to the plasma burner to form~~] forming SiO₂ particles, [~~and the~~] said SiO₂ particles being deposited in layers in the presence of fluorine on a [~~the~~]

cylindrical outer surface of a substrate tube which is rotating about [its] a longitudinal axis thereof and is made from quartz glass, and wherein said particles [being] are sintered, [characterized in that the]

collapsing said cladding glass tube [~~is collapsed~~] onto [the] said core glass cylinder, and

[that the] removing said substrate tube [~~is removed~~] prior to collapsing said cladding glass tube.

7. (currently amended) The method according to claim 6, [characterized in that the] wherein said substrate tube is removed by etching.

8. (currently amended) The method according to claim 6 or 7, [characterized in that the] wherein said substrate tube is etched off during production of the cladding glass tube by introducing an etching gas.

9. (currently amended) The method according to claim 8, [characterized in that] wherein said etching gas is SF₆ [~~is used as the etching gas~~].

10. (currently amended) The method according to claim [~~any one of claims~~] 6 [~~to 9~~], [characterized in that a] wherein said substrate tube [~~is used having~~] has a wall thickness ranging from 2 mm to 10 mm.